Attorney Docket No.: 2102475-991160

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

- 1-18. (cancelled)
- 19. (previously presented) A semiconductor device according to claim 22, further comprising:

a lowermost wiring layer nearest to the semiconductor substrate and provided below the first wiring layer; and

an uppermost wiring layer farthest from the semiconductor substrate and provided above the second wiring layer.

- 20. (previously presented) A semiconductor device according to claim 19, wherein a wiring pitch of the first wiring layer is greater than that of the second wiring layer.
- 21. (previously presented) A semiconductor device according to claim 19, wherein the first wiring layer is a layer on which a power source line is formed.
- 22. (previously presented) A semiconductor device comprising:
 - a semiconductor substrate;
- a first wiring layer having a first thickness and provided above the semiconductor substrate; and
- a second wiring layer having a second thickness thinner than the first thickness and provided above the first wiring layer,

wherein the first wiring layer comprises a first area having signal lines and a second area having power source lines, and a pitch of the power source lines is greater than that of the signal lines.

Gray Cary\EM\7161470.1 2102475-991160 -2-

Attorney Decket No.: 2102475-991160

- 23. (previously presented) A semiconductor device according to claim 19, wherein the first wiring layer comprises a first area having signal lines and a second area having power source lines, and a width of each of the power sources lines is greater than that of the signal lines.
- 24. (previously presented) A semiconductor device according to claim 19, wherein the first wiring layer is substantially as thick as the uppermost wiring layer.
- 25. (previously presented) A semiconductor device according to claim 19, wherein the second wiring layer is substantially as thick as the lowermost wiring layer.
- 26. (previously presented) A semiconductor device according to claim 19, wherein all of the uppermost wiring layer, the lowermost wiring layer and the first and second wiring layers are metal layers.
- 27. (cancelled)
- 28. (previously presented) A semiconductor device according to claim 33, further comprising:

a lowermost wiring layer nearest to the semiconductor substrate and provided below the first wiring layer; and

an uppermost wiring layer farthest from the semiconductor substrate and provided above the second wiring layer.

- 29. (previously presented) A semiconductor device according to claim 28, wherein the first wiring layer is a layer on which a core power source line is formed.
- 30. (previously presented) A semiconductor device according to claim 28, wherein a wiring pitch of the first wiring layer is greater than that of the second wiring layer.
- 31. (previously presented) A semiconductor device according to claim 28, wherein the first wiring layer is substantially as thick as the uppermost wiring layer.

Attorney Docket No.: 2102475-991160

- 32. (previously presented) A semiconductor device according to claim 28, wherein the second wiring layer is substantially as thick as the lowermost wiring layer.
- 33. (previously presented) A semiconductor device comprising:
 - a semiconductor substrate;
 - an IP core area on the semiconductor substrate;
 - a peripheral area on the semiconductor substrate except for the IP core area;
- a first wiring layer having a first thickness and provided above the semiconductor substrate in the IP core area; and
- a second wiring layer having a second thickness smaller than the first thickness and provided above the first wiring layer in the IP core area,

wherein the first wiring layer comprises a first area having signal lines and a second area having power source lines, and a pitch of the power source lines is greater than that of the signal lines.

- 34. (previously presented) A semiconductor device according to claim 28, wherein the first wiring layer comprises a first area having signal lines and a second area having power source lines, and a width of each of the power source lines is greater than that of the signal lines.
- 35. (previously presented) A semiconductor device according to claim 28, wherein all of the uppermost wiring layer, the lowermost wiring layer and the first and second wiring layers are metal layers.
- 36. (previously presented) A semiconductor device comprising:
 - a semiconductor substrate;
- a first wiring layer having a first thickness and provided above the semiconductor substrate; and
- a second wiring layer having a second thickness thinner than the first thickness and provided above the first wiring layer,

Attorney Locket No.: 2102475-991160

wherein the first wiring layer comprises a first area having signal lines and a second area having power source lines, and a width of each of the power sources lines is greater than that of the signal lines.

- 37. (previously presented) A semiconductor device according to claim 36, further comprising:
- a lowermost wiring layer nearest to the semiconductor substrate and provided below the first wiring layer; and

an uppermost witing layer farthest from the semiconductor substrate and provided above the second wiring layer.

- 38. (previously presented) A semiconductor device according to claim 36, wherein a wiring pitch of the first wiring layer is greater than that of the second wiring layer.
- 39. (previously presented) A semiconductor device according to claim 36, wherein the first wiring layer is a layer on which a power source line is formed.
- 40. (previously presented) A semiconductor device according to claim 36, wherein the first wiring layer is substantially as thick as the uppermost wiring layer.
- 41. (previously presented) A semiconductor device according to claim 36, wherein the second wiring layer is substantially as thick as the lowermost wiring layer.
- 42. (previously presented) A semiconductor device according to claim 36, wherein all of the uppermost wiring layer, the lowermost wiring layer and the first and second wiring layers are metal layers.
- 43. (previously presented) A semiconductor device comprising:
 - a semiconductor substrate;
 - an IP core area on the semiconductor substrate;
 - a peripheral area on the semiconductor substrate except for the IP core area;

Attorney Decket No.: 2102475-991160

a first wiring layer having a first thickness and provided above the semiconductor substrate in the IP core area; and

a second wiring layer having a second thickness smaller than the first thickness and provided above the first intermediate wiring layer in the IP core area,

wherein the first wiring layer comprises a first area having signal lines and a second area having power source lines, and a width of each of the power source lines is greater than that of the signal lines.

- 44. (previously presented) A semiconductor device according to claim 43, further comprising:
- a lowermost wiring layer nearest to the semiconductor substrate and provided below the first wiring layer; and

an uppermost wiring layer farthest from the semiconductor substrate and provided above the second wiring layer.

- 45. (previously presented) A semiconductor device according to claim 43, wherein the first wiring layer is a layer on which a core power source line is formed.
- 46. (previously presented) A semiconductor device according to claim 43, wherein a wiring pitch of the first wiring layer is greater than that of the second intermediate wiring layer.
- 47. (previously presented) A semiconductor device according to claim 43, wherein the first wiring layer is substantially as thick as the uppermost wiring layer.
- 48. (previously presented) A semiconductor device according to claim 43, wherein the second wiring layer is substantially as thick as the lowermost wiring layer.
- 49. (previously presented) A semiconductor device according to claim 43, wherein all of the uppermost wiring layer, the lowermost wiring layer and the first and second wiring layers are metal layers.

Attorney Decket No.: 2102475-991160

- 50. (currently amended) A semiconductor device comprising:
 - a semiconductor substrate;
- a first wiring layer having a first thickness, extending in a direction parallel to a surface of the semiconductor substrate, and provided above the semiconductor substrate;
- a second wiring layer having a second thickness greater than the first thickness, extending in the direction, and provided between the semiconductor substrate and the first wiring layer; and
- a third wiring layer having a third thickness greater than the first thickness, extending in the direction, and provided above the first wiring layer,

wherein the first wiring layer comprises a first area having signal lines and each of the second and third wiring layers comprise a second area having power source lines, and a pitch of the power source lines is greater than that of the signal lines.

- 51. (currently amended) A semiconductor device comprising:
 - a semiconductor substrate;
- a first wiring layer having a first thickness, extending in a direction parallel to a surface of the semiconductor substrate, and provided above the semiconductor substrate;
- a second wiring layer having a second thickness smaller than the first thickness, extending the direction, and provided between the semiconductor substrate and the first wiring layer; and
- a third wiring layer having a third thickness smaller than the first thickness, extending in the direction, and provided above the first wiring layer;

wherein the first wiring layer comprises a first area having power source lines, and each of the second and third wiring layers comprise a second area having signal lines, and a pitch of the power source lines is greater than that of the signal lines.